IN THE SPECIFICATION:

Please replace the Abstract with the following amended Abstract:

ABSTRACT

A laser beam [[L1]] emitted from a laser source [[10]] is projected onto a target [[30]] set in a vacuum chamber [[60]] while being focused by a focusing optical system [[20]]. This results in generating fast particles, [[P]] such as protons and emitting the particles from the target [[30]]. A light measuring device [[40]] measures plasma emission [[L2]] from the target [[30]] upon in-focus irradiation with the laser beam [[L1]] and an analyzing device [[50]] analyzes a measurement signal therefrom to assess a generation state of fast particles [[P]]. Then the focusing optical system [[20]] and target [[30]] are controlled through optical system moving mechanism [[25]] and target moving mechanism [[35]] on the basis of the result of the analysis and feedback control is performed on the generation state of fast particles [[P]] in the target [[30]]. This realizes a fast particle generating apparatus capable of monitoring the generation state of fast particles in real time and thereby efficiently generating the fast particles.